

00862.022199



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS,
ELECTRON BEAM LITHOGRAPHY
APPARATUS, EXPOSURE APPARATUS,
EXPOSURE APPARATUS MAINTENANCE
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND SEMI-
CONDUCTOR MANUFACTURING FACTORY

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: Examiner: P. L. Rodriguez
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: Group Art Unit: 2125
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: Confirmation No.: 4154
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: Allowed: November 10, 2004
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: January 27, 2005
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Mail Stop Issue Fee

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 CFR 1.312

Sir:

In response to the Notice of Allowance dated November 10, 2004, please amend the above-identified application as follows: